

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): Branco et al.

Serial No.: 09/617,454

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Title: Method for Cleaning Plasma Etch
Chamber Structures

Attorney Docket No.: CY-0015

Group Art Unit: 1746

Examiner: Markoff, A.

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3/18/03

RESPONSE TO OFFICE ACTION

5 Assistant Commissioner for Patents
Washington, D.C. 2023110 A. Introductory Comments

The following is submitted in response to the Office Action dated December 18, 2002, and is currently due March 18, 2003.

15 This response is presented in the revised amendment format set forth in 1265 Off. Gaz. Pat. Office 87 (Dec. 17, 2002) and so is subject to waiver of the provisions of 37 C.F.R. §1.21(a), (b) and (c).

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37 C.F.R. §1.8

I hereby certify that this correspondence is being

30 [X] transmitted via facsimile to the United States Patent and Trademark Office to fax number: 1-703-872-9310
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